## Sensing amorphous/crystalline silicon surface passivation by attenuated total reflection infrared spectroscopy of amorphous silicon on glass \*

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Attenuated total reflection Fourier transform infrared (ATR FTIR) spectroscopy and effective lifetime measurements have been used to characterize amorphous/crystalline silicon surface passivation in silicon heterojunction solar cells. The comparative studies show a strong link between microstructure factor  $R^*$  and effective lifetime of amorphous silicon (*a*-Si:H) passivation layers incorporating an interface buffer layer, which prevents the epitaxial growth. It is demonstrated that thin *a*-Si:H films deposited on glass can be used as ATR substrates in this case. The obtained results show that *a*-Si:H films with  $R^*$  close to 0.1 are required for manufacturing of high-efficiency (> 23%) silicon heterojunction solar cells.

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